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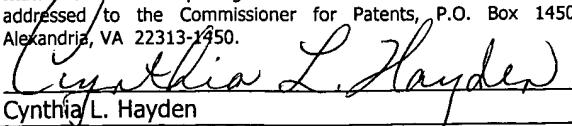
Applicant: Justin K. Brask et al. § Art Unit: 2811
Serial No.: 10/626,336 § Examiner: Ori Nadav
Filed: July 24, 2003 §
For: Forming a High Dielectric Constant § Atty Docket: ITL.1022US
Film Using Metallic Precursor § P16709
§

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO PAPER NO. 0

Sir:

In response to the office action mailed September 24, 2004, please amend the above-referenced patent application as follows:

Date of Deposit: <u>December 1, 2004</u>
I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Cynthia L. Hayden